TC Chapter Announcements

Gases Japan TC Chapter:
SEMI Japan Standards Summer 2017 Meetings
Friday, June 23, 2017, 15:00-17:00
SEMI Japan, Tokyo, Japan

Facilities Japan TC Chapter:
SEMI Japan Standards Summer 2017 Meetings
Friday, June 23, 2017, 15:00-17:00
SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs of Gases Japan TC Chapter: Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan)
Co-Chairs of Facilities Japan TC Chapter: Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan)
SEMI Staff: Naoko Tejima (SEMI Japan)

<table>
<thead>
<tr>
<th>Company</th>
<th>Last</th>
<th>First</th>
<th>Company</th>
<th>Last</th>
<th>First</th>
</tr>
</thead>
<tbody>
<tr>
<td>Hitachi High Technologies</td>
<td>Enami</td>
<td>Hiromichi</td>
<td>Tokyo Electron Yamanashi</td>
<td>Moriya</td>
<td>Shuji</td>
</tr>
<tr>
<td>Tri Chemical Laboratories Inc.</td>
<td>Hiraki</td>
<td>Tadaaki</td>
<td>HORIBA STEC</td>
<td>Shimizu</td>
<td>Tetsuo</td>
</tr>
<tr>
<td>Fujikin</td>
<td>Hirose</td>
<td>Takashi</td>
<td>MKS Japan</td>
<td>Suzuki</td>
<td>Isao</td>
</tr>
<tr>
<td>Hitachi Metals</td>
<td>Jinbo</td>
<td>Katsuhiro</td>
<td>SEMI Japan</td>
<td>Tejima</td>
<td>Naoko</td>
</tr>
<tr>
<td>Fujikin</td>
<td>Kitano</td>
<td>Masashi</td>
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</tbody>
</table>

* alphabetical order by last name

Table 2 Leadership Changes

Gases Japan TC Chapter
None.

Facilities Japan TC Chapter
None.

Table 3 Ballot Results

Gases Japan TC Chapter
None.

Facilities Japan TC Chapter
None.
Table 4 Authorized Activities  
**Gases Japan TC Chapter**  
None.

**Facilities Japan TC Chapter**  
None.

Table 5 Authorized Ballots  
**Gases Japan TC Chapter**  
None.

**Facilities Japan TC Chapter**  
None.

Table 6 New Action Items  
**Gases Japan TC Chapter**  
None.

**Facilities Japan TC Chapter**  
None.

Table 7 Previous Meeting Action Items  
**Gases Japan TC Chapter**

<table>
<thead>
<tr>
<th>Item #</th>
<th>Assigned to</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>Gas161213-1</td>
<td>SEMI Staff</td>
<td>To watch the progress of <em>Doc.5155, New Standard, Guide for Facilities Data Package for Semiconductor Equipment Installation</em> by Building Information Modeling (BIM) for Semiconductor Capital Equipment TF of NA … Open</td>
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**Facilities Japan TC Chapter**  
None.

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[Common Part 1]

1 Welcome, Reminders, and Introductions

Isao Suzuki, committee co-chair, called the meeting to order at 15:00. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

**Motion:** To approve the minutes of the previous meeting as written.

**By / 2nd:** Tetsuo Shimizu (HORIBA STEC) / Shuji Moriya (Tokyo Electron Yamanashi)

**Discussion:** None

**Vote:** 7 in favor and 0 opposed. **Motion passed.**

**Attachment:** 01_JA_G+F_Previous_MtgMinutes_170324

3 SEMI Staff Report


**Attachment:** 02_SEMI_Staff_Report_170324
4 Liaison Reports

4.1 Facilities North America TC Chapter
Naoko Tejima reported for the Facilities North America TC Chapter that no report was provided, since there were not particular and updated things.

4.2 Gases North America TC Chapter
Naoko Tejima reported for the Gases North America TC Chapter that no report was provided, since there were not particular and updated things.

4.3 Gases Europe TC Chapter Report
Naoko Tejima reported for the Gases EU TC Chapter that no report was provided, since there were not particular and updated things.

4.4 Facilities Korea TC Chapter Report
Naoko Tejima reported for the Facilities Korea TC Chapter that no report was provided, since there were not particular and updated things.

[Gases Japan TC Chapter Part]

5 Subcommittee and Task Force Reports

5.1 Gas Panel and Metal Seal Test Methods Task Force
Shuji Moriya reported for the Gas Panel and Metal Seal Test Methods Task Force that there were not particular activities.

5.2 5-year-review Task Force
No Report was provided.

5.3 Live Gas Flow Rate Task Force
Tetsuo Shimizu reported for the Live Gas Flow Rate Task Force. The Task Force met earlier in the day. Of note:

- A round-robin test between MFC makers with critical nozzle was made and all test was finished, and the results were reviewed.
- The next step will be discussed at the next meeting.

6 Old Business

6.1 Previous Meeting Action Items
Naoko Tejima reviewed the previous meeting action items.

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</table>

7 New Business

None.

[Facilities Japan TC Chapter Part]

8 Task Force Reports

8.1 F1 Revision Task Force
No Report was provided.
9 Old Business
9.1 Previous Meeting Action Items
Naoko Tejima reviewed the previous meeting action items.

Table 9 Previous Meeting Actions Items
None.

10 New Business
None.

[Common Part 2]
11 Action Item Review
11.1 New Action Items
Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

12 Next Meeting and Adjournment
The next meeting of the Gases Japan TC Chapter is scheduled for Friday, June 23, 2017, 15:00-17:00, SEMI Japan, Tokyo, Japan.
The next meeting of the Facilities Japan TC Chapter is scheduled for Friday, June 23, 2017, 15:00-17:00, SEMI Japan, Tokyo, Japan.
See http://www.semi.org/en/events for the current list of meeting schedules.
Having no further business, a motion was made to adjourn. Adjournment was at 17:00.
Respectfully submitted by:
Naoko Tejima
Manager, Standards
SEMI Japan
Phone: +81.3.3222.5804
Email: ntejima@semi.org

Minutes approved by:

<table>
<thead>
<tr>
<th>Name</th>
<th>Date</th>
</tr>
</thead>
<tbody>
<tr>
<td>Hiromichi Enami (Hitachi High Technologies), Co-chairs</td>
<td>June 13, 2017</td>
</tr>
<tr>
<td>Isao Suzuki (MKS Japan), Co-chairs</td>
<td>June 12, 2017</td>
</tr>
</tbody>
</table>

Table 10 Index of Available Attachments

<table>
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<tbody>
<tr>
<td>1</td>
<td>JA_G+F_Previous_Mtg_Minutes_170324</td>
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<tr>
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<td>SEMI_Staff_Report_170324</td>
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#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Naoko TEJIMA at the contact information above.